

ABSTRACT OF THE DISCLOSURE

5 A defect inspection system according to the
present invention comprises image acquiring section for
acquiring a two-dimensional image of a subject which is
a processing target in a manufacturing process, defect
extracting section for extracting a defect by a defect
extraction algorithm using a predetermined parameter
for an image acquired by the image acquiring section,
displaying section for displaying an image of a defect
10 of the subject extracted by the defect extracting
section, parameter adjusting section for adjusting the
parameter in accordance with a defect extraction degree
for the subject, and quality judging section for
judging the quality of the subject based on a defect
15 information extracted by the defect extracting section.

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